

Supporting Information

A Universal Strategy to Improve the Mechanical Stability of Flexible

Organic Thin Film Transistor

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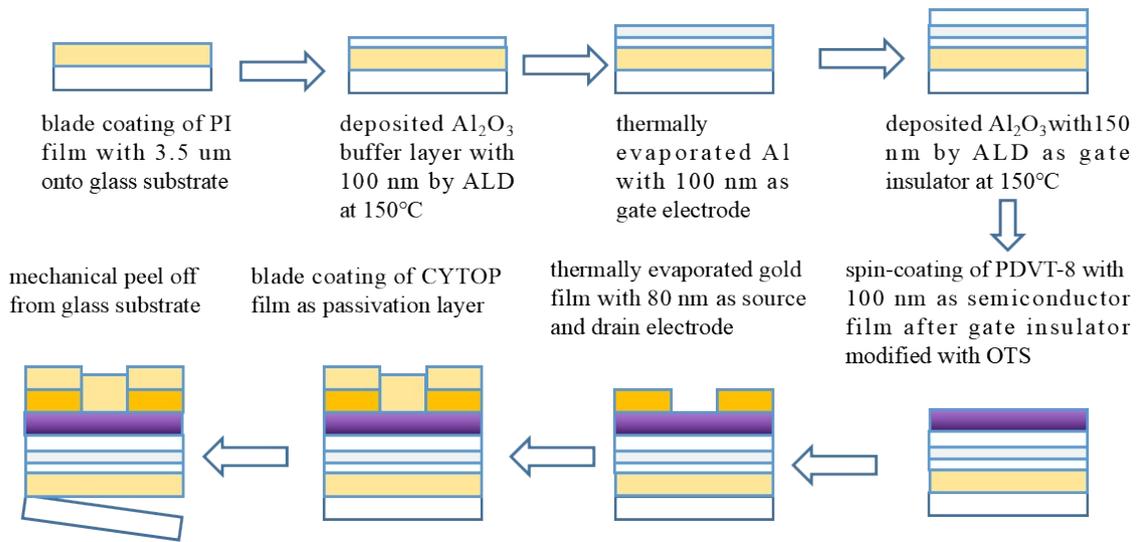


Fig. S1 The fabrication process flow diagram of flexible OTFT.

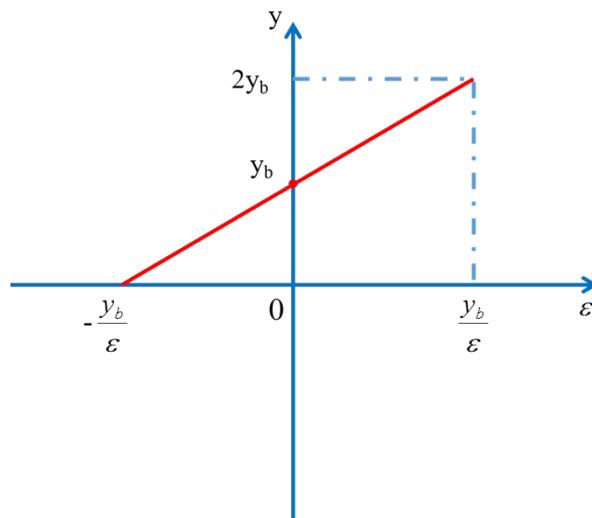


Fig. S2 The relationship between bending strain and the position of bending axis.

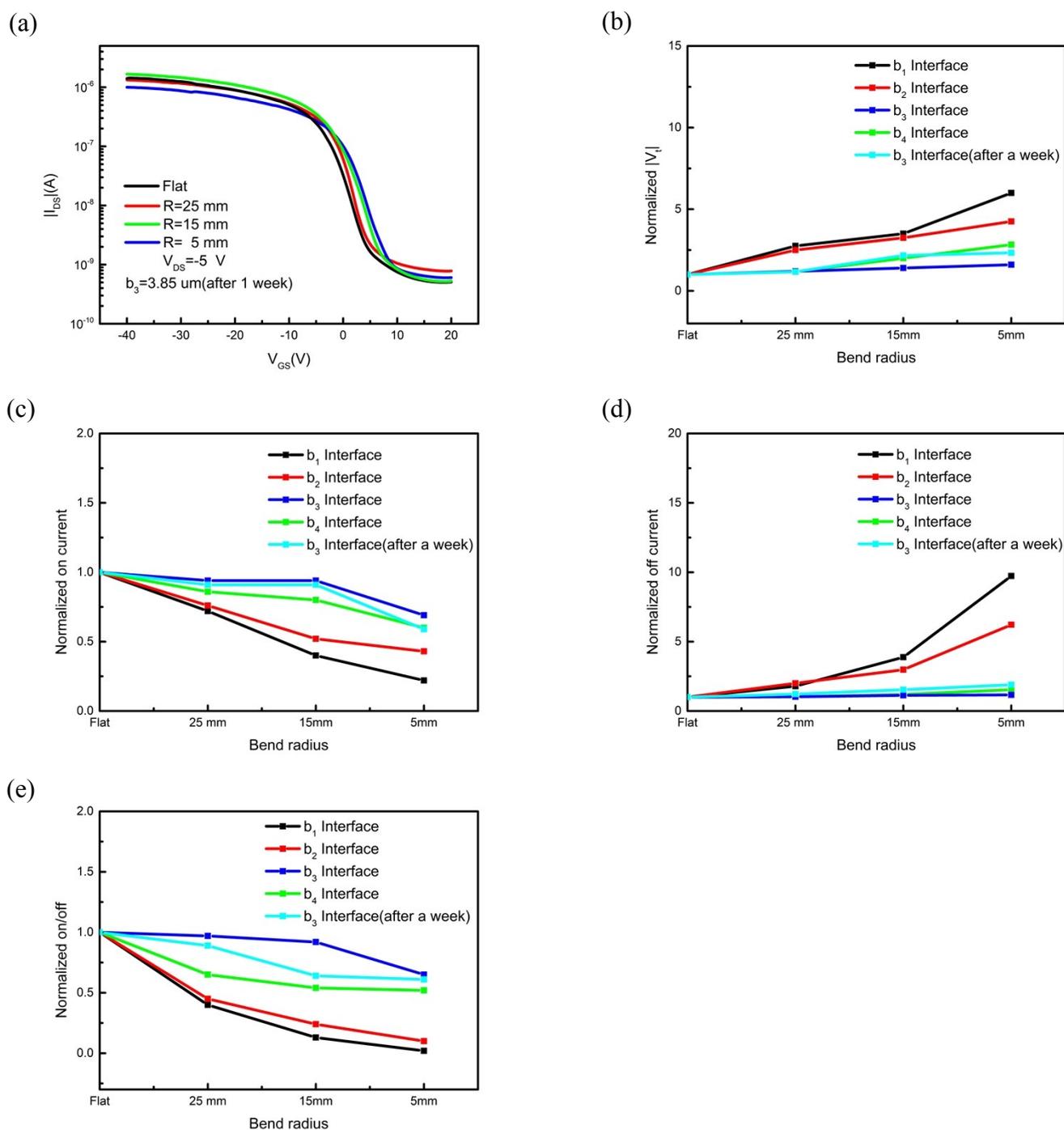


Fig. S3 Transfer characteristic curves of flexible OTFTs with (a) bending axis located at b_3 interface for a week under different bending radius, and the curves of (b) normalized threshold voltage, (c) normalized on current, (d) normalized off current, and (e) normalized on/off current ratio of bending axis located at different interfaces as a function of bending radius.

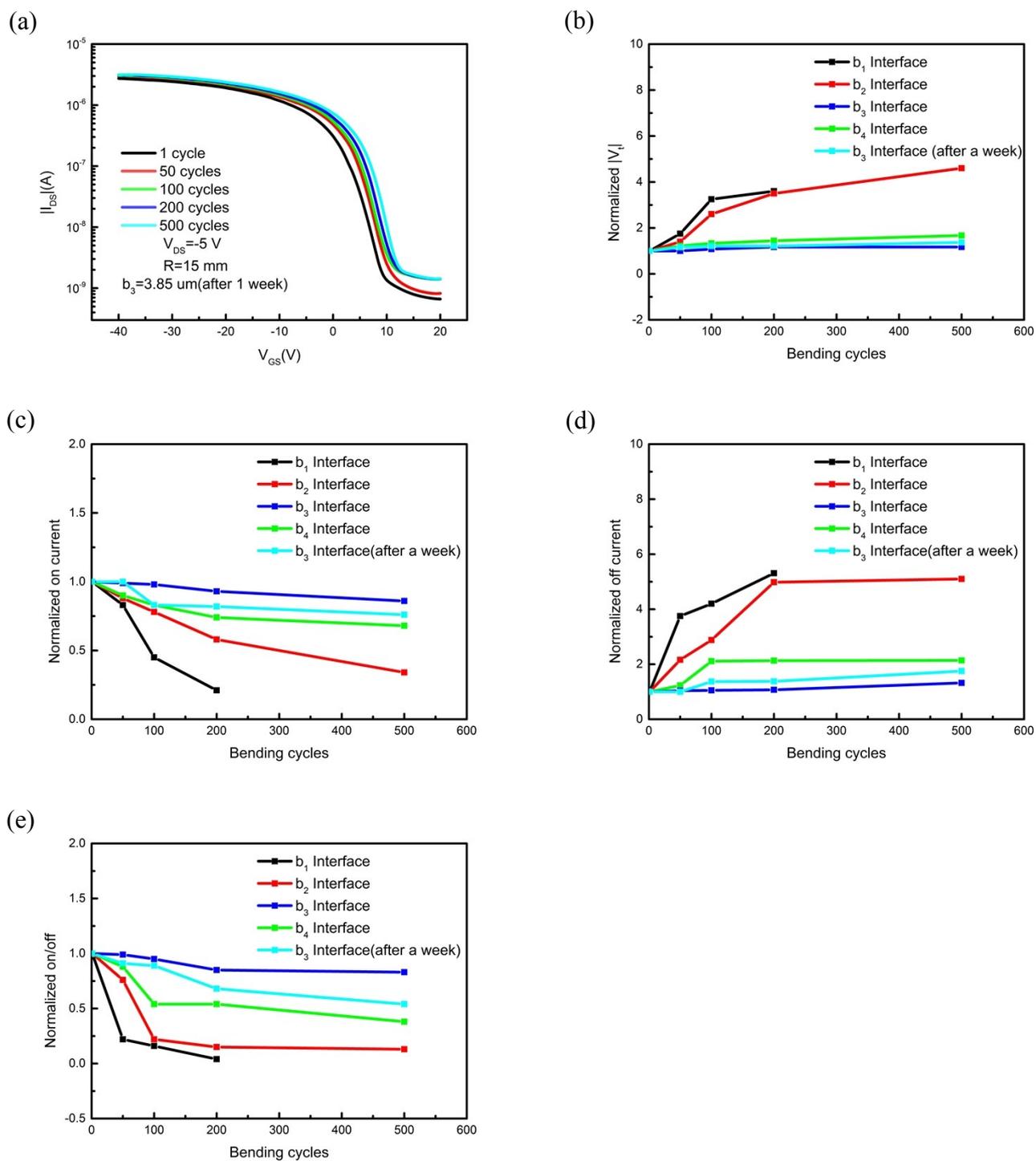


Fig. S4 Transfer characteristic curves of flexible OTFTs with (a) bending axis located at b_3 interface for a week under different bending cycles, and the curves of (b) normalized threshold voltage, (c) normalized on current, (d) normalized off current, and (e) normalized current on/off ratio of bending axis located at different interfaces as a function of bending cycles.

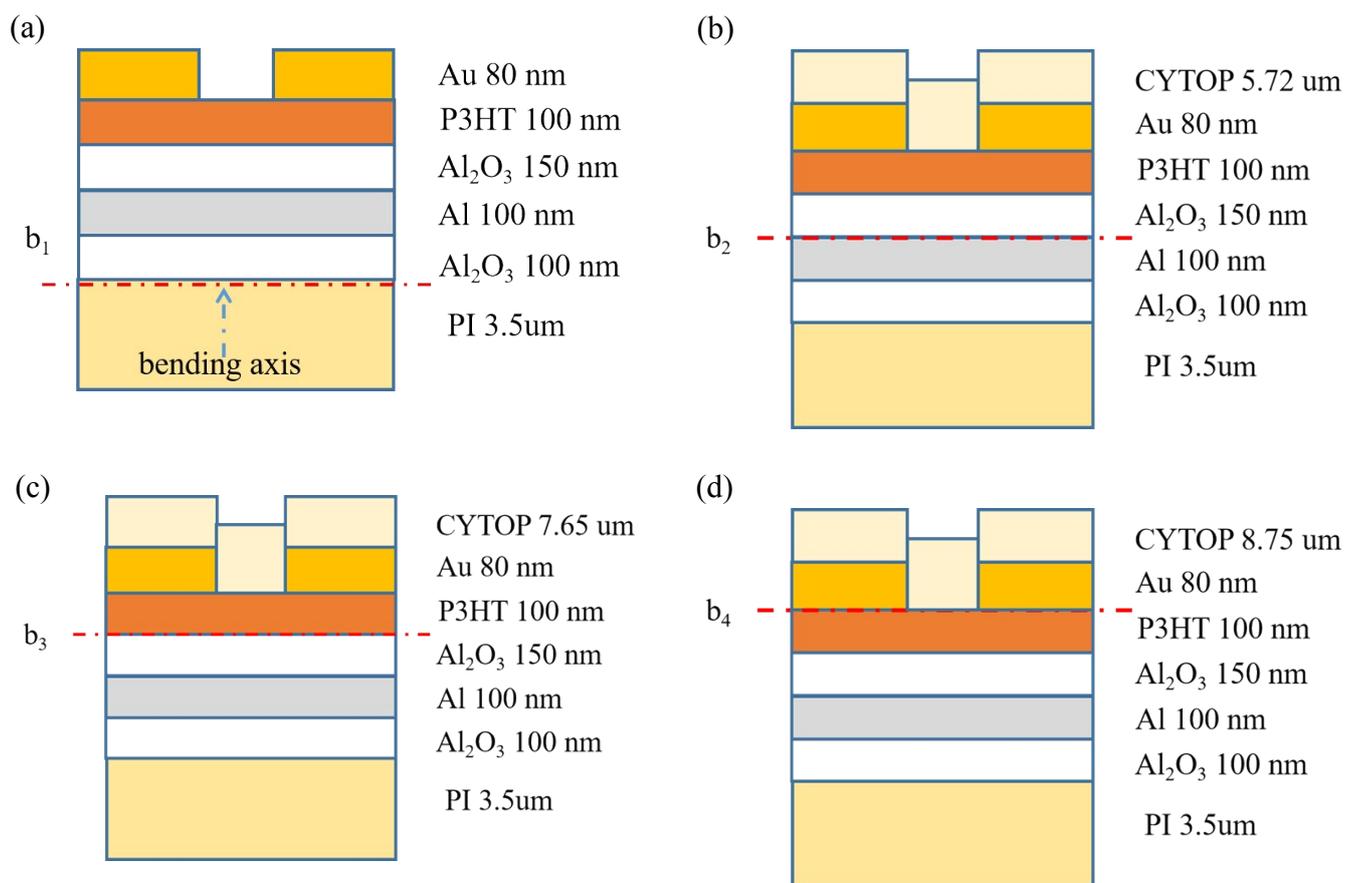


Fig. S5 Position of the bending axis for different flexible OTFTs based on P3HT.

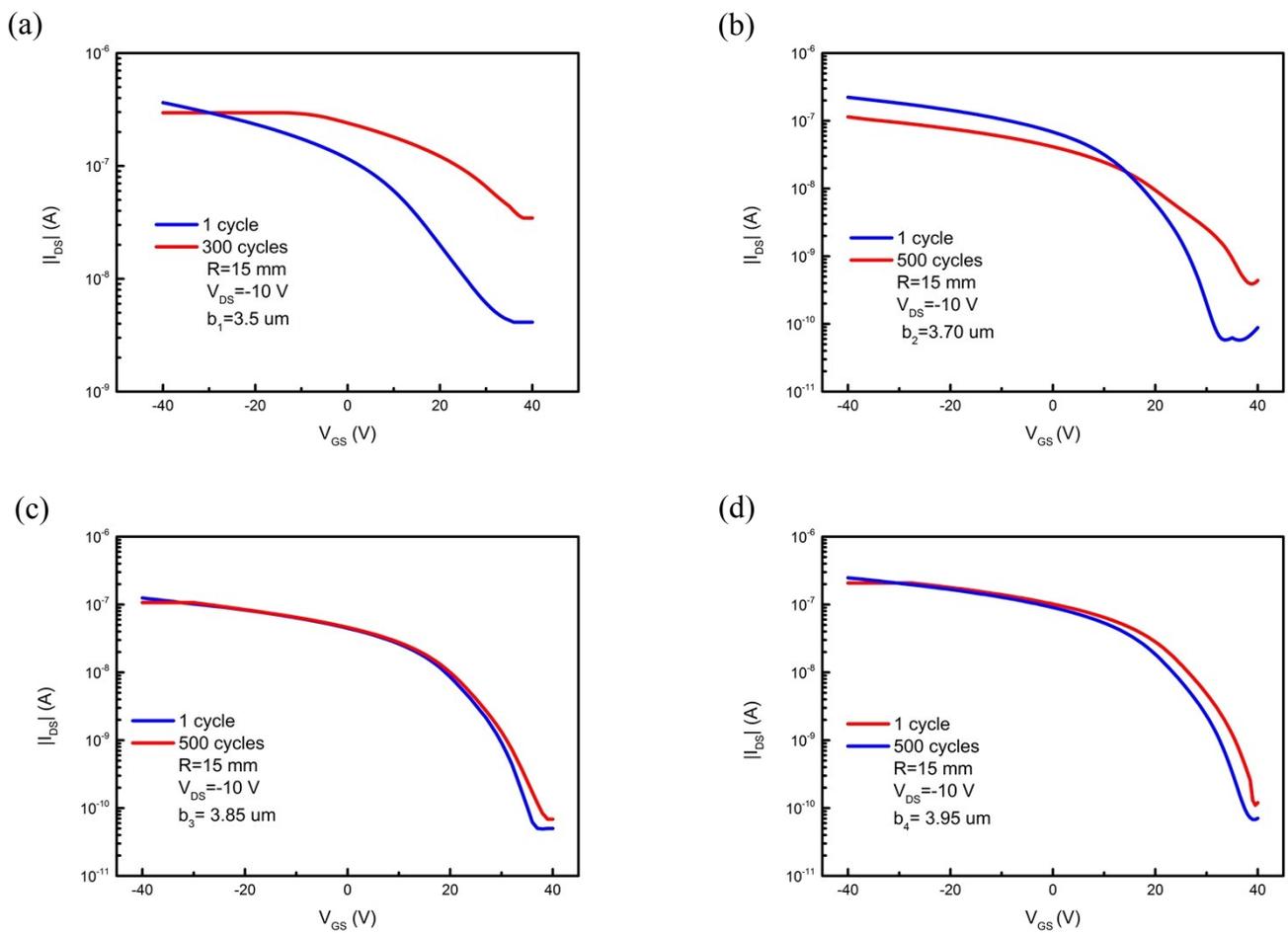


Fig. S6 Transfer characteristic curves of flexible OTFTs based on P3HT with bending axis located at (a) b_1 interface, (b) b_2 interface, (c) b_3 interface, and (d) at b_4 interface under different bending cycles.